



AMENDMENTS TO THE CLAIMS

A2
Claim 1 (original): A wafer processing system comprising:

a loading station;

a process module maintained at a predetermined pressure during normal operation;

and

a first single-wafer load lock directly adjacent to the process module, the first single-wafer load lock having a single wafer support, the first single-wafer load lock being coupled to receive a wafer originating from the loading station.

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Claim 2 (original): The system of claim 1 further including a second single-wafer load lock directly adjacent to said process module, the second single-wafer load lock having a single wafer support.

Claim 3 (original): The system of claim 1 wherein the process module includes a plurality of processing stations.

Claim 4 (original): The system of claim 1 wherein the loading station includes a front-opening unified pod (FOUP).

Claim 5 (original): The system of claim 1 further comprising a robot between the loading station and the first single-wafer load lock.

Claim 6 (original): The system of claim 2 further comprising a pump coupled only to the first and second single-wafer load locks, the pump being located locally on the wafer processing system.

Claim 7 (original): The system of claim 1 wherein the single wafer support of the first single-wafer load lock includes a pedestal having an integral cooling unit.

Claim 8 (original): The system of claim 1 wherein the single wafer support of the first single-wafer load lock includes a single pedestal having an integral heating unit.

Claims 9-12 (cancelled)

Claim 13 (original): A wafer processing system comprising:

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- a loading station;
 - a process module maintained at vacuum during normal processing;
 - a plurality of load locks, each of the plurality of load locks having an opening in direct communication with the process module and another opening in communication with the loading station; and
 - a robot between the loading station and the plurality of load locks, the robot capable of transferring a wafer from the loading station to a load lock in the plurality of load locks.

Claim 14 (original): The system of claim 13 wherein a first load lock in the plurality of load locks is a single-wafer load lock.

Claim 15 (original): The system of claim 14 wherein the first load lock includes a single pedestal having an integrated cooling unit.

Claim 16 (original): The system of claim 14 wherein the first load lock includes a single pedestal having an integrated heating unit.

Claim 17 (original): The system of claim 13 wherein the robot is an atmospheric robot.

Claim 18 (original): The system of claim 13 wherein the loading station is a front-opening unified pod (FOUP).

Claim 19 (original): The system of claim 13 wherein the process module has a plurality of processing stations.

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Claim 20 (original): The system of claim 19 wherein at least one of the plurality of processing stations is capable of heating a supported wafer.

